



Application Serial No. 10/085,759  
File No. NMTI 1002-6 US

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Assistant Commissioner for Patents, Washington, D.C. 20231, on 31 October 2002.

Kathryn Marley  
Kathryn Marley

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of: **Michel Luc Cote et al.**

Examiner: Unknown

Application No.: **10/085,759**

Group: Unknown

Filed: **28 February 2002**

Title: **Design and Layout of Phase Shifting  
Photolithographic Masks**

**PRELIMINARY AMENDMENT**

Assistant Commissioner for Patents  
Washington, DC 20231

Sir:

Please amend the subject patent application as follows.

In the Specification:

Please change page 1, paragraph 4 to read as follows:

*A1*  
This application is a continuation-in- part of, and incorporates by reference, the <sup>now U.S. Patent No. 6,503,666</sup> ~~now U.S. Patent No. 6,503,666~~ United States Patent Application Serial No. 09/669,359 filed 26 Sep 2000 entitled "Phase Shift Masking for Complex Patterns" having inventor Christophe Pierrat and assigned to the assignee of the present invention, which is related to United States Provisional Patent Application Serial No. 60/215,938 filed 5 Jul 2000 entitled "Phase Shift Masking For Complex Layouts" having inventor Christophe Pierrat and assigned to the assignee of the present invention.

*AP(214/04)*